



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Shinichiro KOTAKE, et al.
Title: FLUE GAS TREATING SYSTEM AND PROCESS
Appl. No.: 09/658,928
Filing Date: September 11, 2000
Examiner: Wayne A. Langel
Art Unit: 1754

AMENDMENT AND RESPONSE UNDER 37 C.F.R. §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

This is a response to the Office Action mailed on March 9, 2004, in connection with the captioned application.

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this document.

Remarks begin on page 6 of this document.

06/10/2004 AADDF01 00000089 09658928

01-FC:1801
02-FC:1203

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